EAST Search History (Interference)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L9	4	((wafer or semiconductor or substrate) nozzle near7 mix near7 gas near7 liquid).clm.	US-PGPUB; UPAD	AND	ON	2011/06/29 15:49
L10	6	((wafer or semiconductor or substrate) nozzle mix near7 gas near7 liquid).clm.	US-PGPUB; UPAD	AND	ON	2011/06/29 15:50
L11	62	((wafer or semiconductor or substrate) nozzle mix$3 near7 gas near7 liquid).clm.	US-PGPUB; UPAD	AND	ON	2011/06/29 15:50
L12	30	((wafer or semiconductor or substrate) nozzle mix$3 near7 gas near7 liquid step$3).clm.	US-PGPUB; UPAD	AND	ON	2011/06/29 15:52
L13	1	((wafer or semiconductor or substrate) nozzle mix$3 near7 gas near7 liquid step$3 near8 (port or passage)).clm.	US-PGPUB; UPAD	AND	ON	2011/06/29 15:52
L14	11	((wafer or semiconductor or substrate) nozzle mix$3 near7 gas near7 liquid (port or passage) near5 (gas and liquid)).clm.	US-PGPUB; UPAD	AND	ON	2011/06/29 15:53